



Atty. Dkt. No. AMAT/5083/CMP/CMP/RKK

PATENT #5/A

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MAY 29 2003
TC 1700

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Wang, et al.

Serial No.: 09/842,476

Confirmation No.: 7917

Filed: April 25, 2001

For: Chemical Mechanical Polishing
Composition and Process

Group Art Unit: 1765

Examiner: L.T. Umez Eronini

Mail Stop Non-Fee Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

CERTIFICATE OF MAILING 37 CFR 1.8

I hereby certify that this correspondence is being deposited on May 22, 2003, with the United States Postal Service as First Class Mail in an envelope addressed to: Mail Stop Non-Fee Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

5/22/03
Date

Kurt R. Zuber
Signature

Dear Sir:

RESPONSE TO OFFICE ACTION DATED APRIL 29, 2003

In response to the Office Action dated April 29, 2003, having a shortened statutory period for response set to expire on May 29, 2003, Applicants elect Claims 1-16 and 27-32, Group I with traverse, and request reconsideration of the restriction requirement for the reasons discussed below. Although Applicant believes that no fee is due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/5083/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE CLAIMS:

Please amend the claims as follows: